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FACSIMILE TRANSMISSION

CONFIDENTIAL

DATE: February 25, 2005

CLIENT-MATTER NO.: 20830-08288

To:

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FROM:

John T. McNelis

PHONE:

(650) 335-7133

NUMBER OF PAGES WITH COVER PAGE: 9

ORIGINAL WILL NOT FOLLOW

MESSAGE:

Applicants: Steven W. Meeks, et al.

App. No. 10/660,984

Filing Date: September 12, 2003

TITLE: System And Method For Simultaneously Measuring Thin Film Layer Thickness,

Reflectivity, Roughness, Surface Profile And Magnetic Pattern On Thin Film Magnetic Disks

And Silicon Wafers

Atty. Dkt. No.: 20830-08288

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20830/08288/DOCS/1502147.1

	Application Number 10	0/660,984				
•	Filling Date Se	September 12, 2003				
TRANSMITTAL FORM		Steven W. Meeks				
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(to be used for all correspondence during pendency of filed application)	Group Art Unit Number 2	2877				
·	Examiner Name T	u T. Nguyen				
Total Number of Pages in This Submission 8	Attorney Docket Number 26	0830-08288				
ENCLOSURES	(check all that apply)					
Fee Transmittal Form (in duplicate)	Issue Fee Transmitt	ai .				
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Response to Notice to File Missing Parts	[] Sheet(s) of					
Assignment & Recordation Cover Sheet	Appeal Communication to Board of Appeals and Interferences					
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Copies of IDS Cited References		mmunication to Group				
Request for Corrected Filing Receipt	Filing Receipt					
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Amendment/Response: [] Page(s)	Communication After Notice Of Allowance					
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IN THE UNITED STATES

PATENT AND TRADEMARK OFFICE

APPLICANT(S):

Steven W. Meeks et al.

APPLICATION NO.:

10/660,984

FILING DATE:

September 12, 2003

TITLE:

System And Method For Simultaneously Measuring Thin Film

Layer Thickness, Reflectivity, Roughness, Surface Profile And Magnetic Pattern On Thin Film Magnetic Disks And Silicon

Wafers

EXAMINER:

Tu T. Nguyen

GROUP ART UNIT:

2877

ATTY. DKT. NO.:

20830-08288

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Signature:	John J. N					
Typed or Printed Name:	John T. McNelis	Dated:	25 Feb 2005			
Facsimile Number.	(703) 872-9306					

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REQUEST FOR CORRECTED FILING RECEIPT AND COMMUNICATION AFTER NOTICE OF ALLOWANCE

SIR:

Enclosed is a copy of the Official Filing Receipt. It contains the following error:

1. The Applicant's name is erroneously stated as Rusmin Kadinar. The correct Applicant's name is Rusmin Kudinar as evidenced by the executed Declaration, a copy of which is enclosed.

20830/08288/DOCS/1502132.1

Applicants erroneously but in good faith filed an IDS under 37 CFR 1.56 on 2. February 4, 2005. The undersigned attorney was not aware at that time that a Notice of Allowance was pending. Accordingly, Applicants request that the references cited in the February 4, 2005 IDS be placed in the file although they may not be considered by the Examiner

Please issue a corrected Filing Receipt rectifying this error.

Respectfully submitted, STEVEN W. MEEKS et al.

Dated: 25 Feb 2005

John Tk McNelis, Reg. No.: 37,186

650 938 5200

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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY.DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/660 984	09/12/2003	2877	675	20830-08288	27	1	1

CONFIRMATION NO. 6114

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MOUNTAIN VIEW, CA 94041

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FENWICK & WEST LLP

FILING RECEIPT

"OC000000011425513"

Date Mailed: 12/08/2003

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filling Receipt, please write to the Office of Initial Patent Examination's Filling Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filling Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filling Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filling Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

45

Steven W. Meeks, San Jose, CA; Rusmin-Kadinar, Union City, CA; Kudinax

Domestic Priority data as claimed by applicant

This application is a CON of 09/414,388 10/07/1999 PAT 6,665,078 which is a CIP of 09/347,622 07/02/1999 which is a CIP of 09/136,897 08/19/1998 PAT 6,031,615 which claims benefit of 60/059,740 09/22/1997

Foreign Applications

If Required, Foreign Filing License Granted: 12/03/2003

Projected Publication Date: 03/11/2004

Non-Publication Request: No

Early Publication Request: No

** SMALL ENTITY **

Title

System and method for simultaneously measuring thin film layer thickness, reflectivity, roughness. surface profile and magnetic pattern on thin film magnetic disks and silicon wafers

Preliminary Class

356

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